

How High-Speed Probe Cards Accelerate Time-to-Market

micron

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Outline

- Introduction / Background
- Accelerating Cycles of Learning
- High-Speed Probe Card Definition and Use Cases
- Advancing High-Speed Probe Technology
- Key Challenges for High-Speed Probing
- Summary / Conclusion

Introduction / Background

Problem statement:

- Memory manufacturers in a <u>race</u> to release newest technology to market (e.g.: DDR6).
- Full cycles of learning require months from tape-out to packaged part testing.
- Once detected, designers need to fix circuit errors, tape-out new reticle, start more wafers.
- How to detect and fix circuit errors faster?



Does Design Meet Specifications?

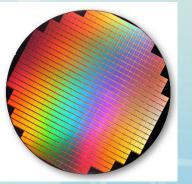
- Verilog simulation
 - Not all circuit errors detected
- Physical application testing
 - Errors not caught in simulation identified by physical testing

-or-

- Testing Methods:
 - High-Speed Package test



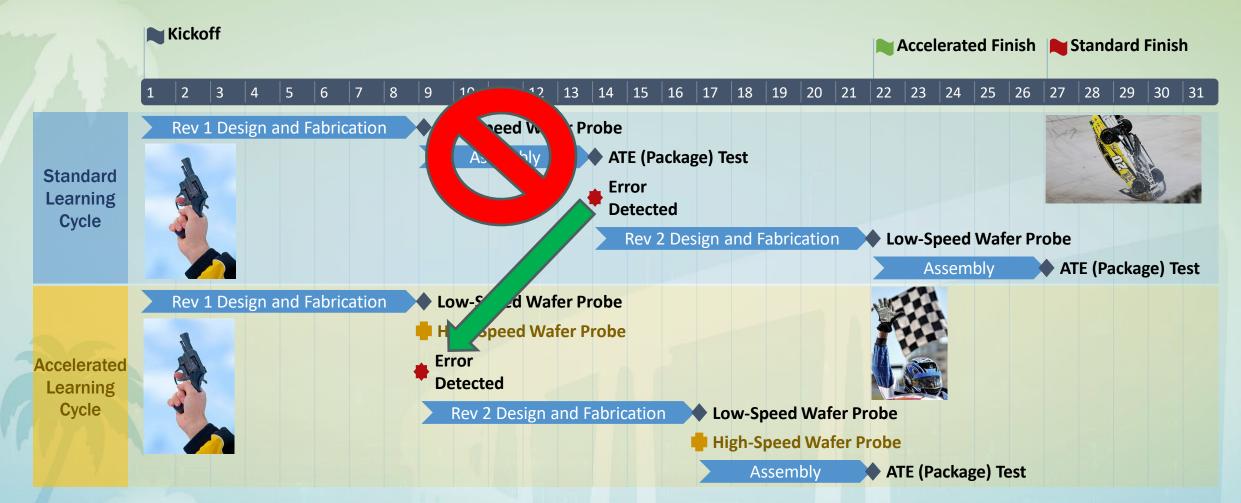




High-Speed Wafer test

\$

Accelerating Cycles of Learning



Time-to-market savings realized!

High-Speed Memory Probe Card Definition

- DRAM Datasheet Speed
- All signal & many PWR/GND pads probed
- Capable of native, customer mode testing
- Full datasheet range of voltages and register combinations
- Card circuitry optimized for signal and power integrity
- Full wafer automated probing for volume data



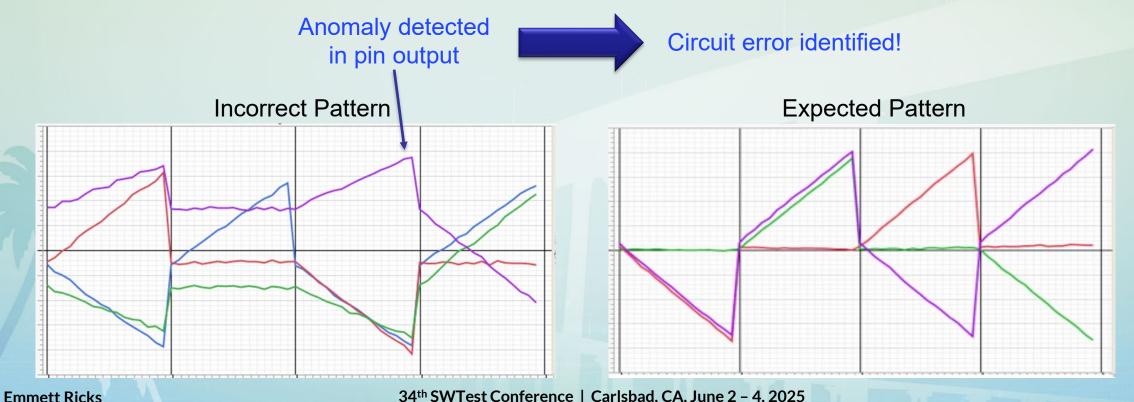
High-Speed Probe Card Use Cases

- Accelerate design revision
 - 1st Silicon debug
 - New Reticle verification
- Regular line sampling
 - Silicon health monitoring (speed yield, datasheet char)

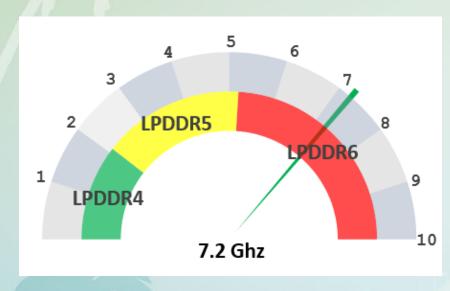
- Bench-level speed characterization on wafer
 - Single die, engineering only

Case Study: Duty Cycle Adjust Circuit Error

- Package test flow emulation using low-speed testers is challenging
- High-Speed wafer tester can evaluate all DRAM circuitry
- Duty Cycle Adjust (DCA) circuit error found using High-Speed tester:



Advancing High-Speed Probe Technology



• Solutions:

- Tester and test program development
 - Signal training, termination, etc.
 - Hardware improvements
- Signal and Power Integrity improvement:
 - Reduction of return loss
 - Reduction of insertion loss
 - Maximization of power probe count
 - Supplier collaboration for Probe Card optimization

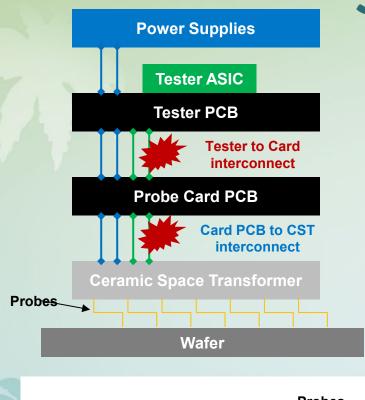
Results:

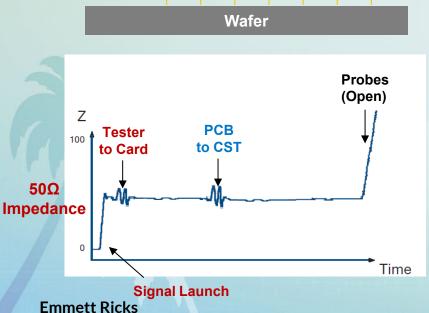
- Comparison of Data Eye shmoofor wafer vs. package
- Statistical Comparison of wafer vs. package results

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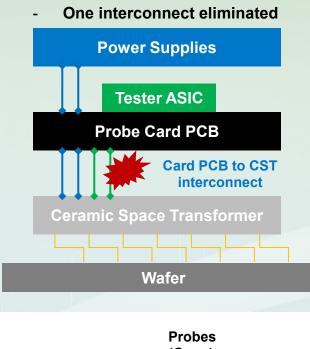
Worst Case

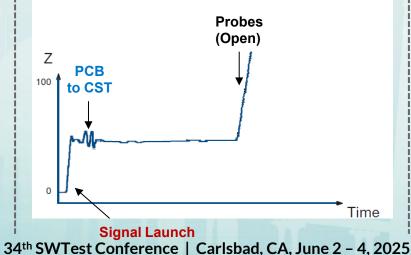
Solution: Return Loss Reduction





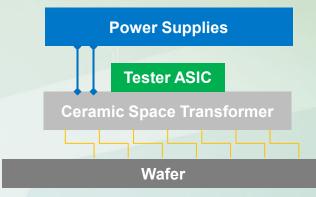
Improved

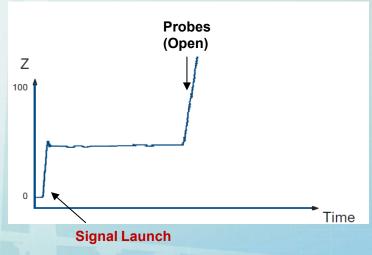




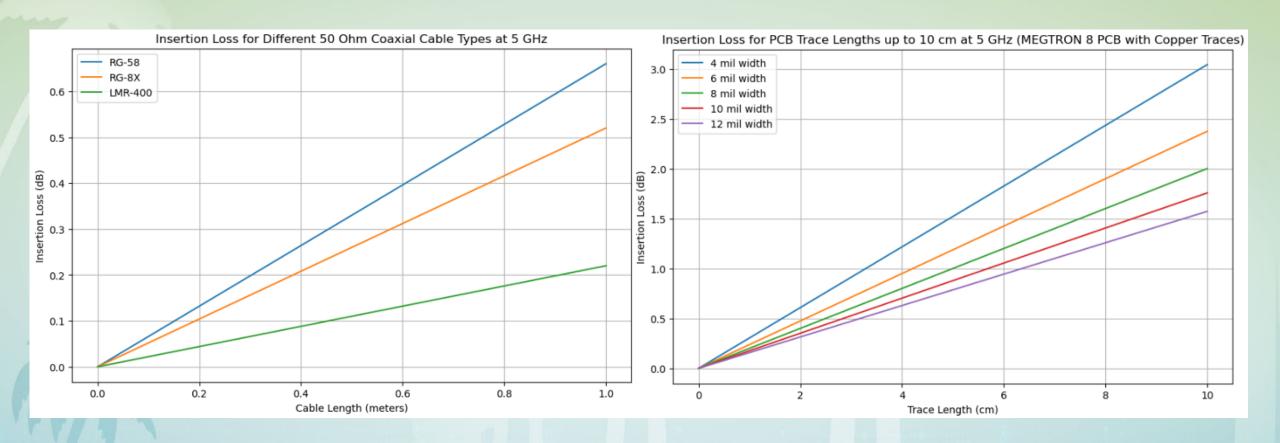
Ideal

- Two interconnects eliminated
- No PCBs





Solution: Insertion Loss Reduction

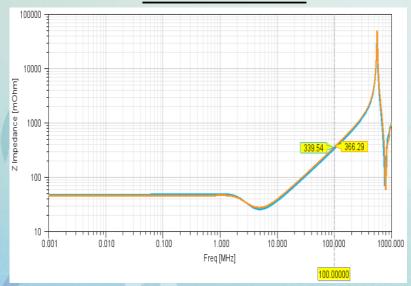


Eliminating cables, shortening PCB traces = less insertion loss!

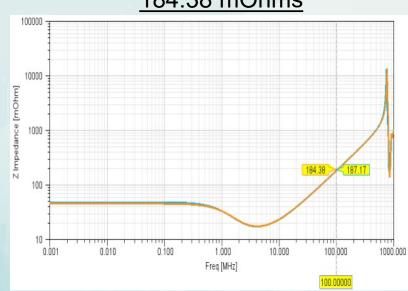
Solution: Maximize Power Probe Count

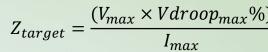
- E.g.: Target Impedance = 500 mOhms @100Mhz
- 2 ports tested (near and far)
- 3X more probes ≈ 35% lower impedance

12 probes, 2x1uF caps 366.29 mOhms



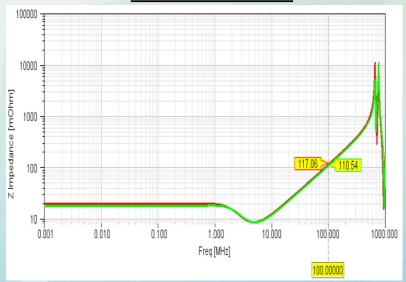
12 probes, 6x1uF caps 184.38 mOhms





- Where:
 - Vdroop max = 3%
 - E.g.: 1V * 3% / 60mA = **500 mOhms**

39 probes, 6x1uF caps 117.06 mOhms



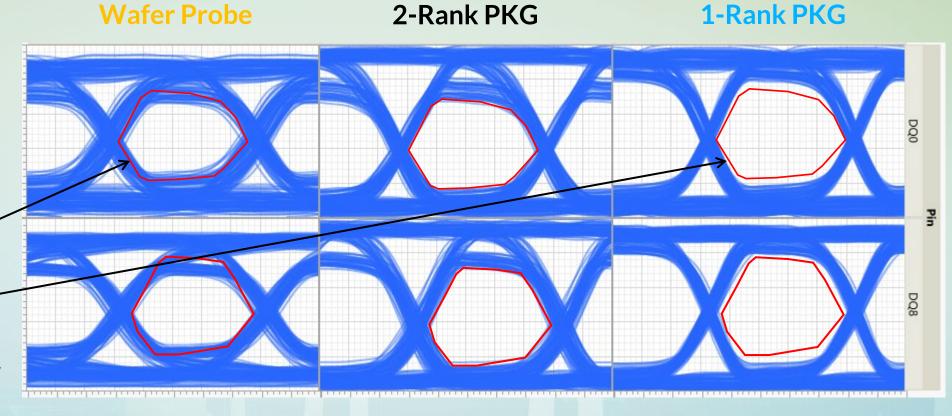
Results: Read Data Eye Comparison

Test Conditions:

- 2 DQ's
- Comparable test conditions between wafer and package.

Note:

Wafer Probe eye collapsed vs.
 1-Rank PKG mainly as function of probe CRES and proximity to tester.



Equivalent width and acceptable height vs. package → qualified

Results: Statistical Comparison

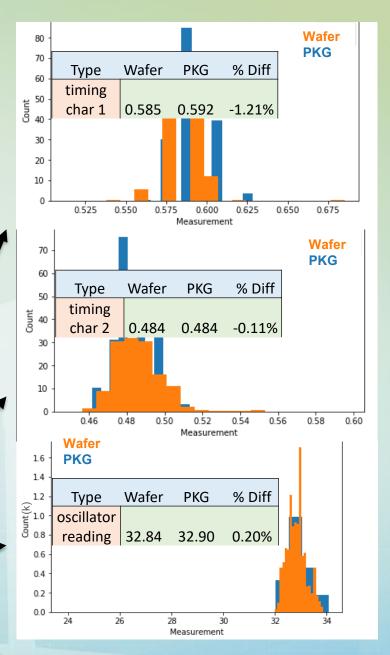
- Several lots probed with High-Speed tester
- 24K passing die packaged and tested

Speed test correlation: ~99.74%



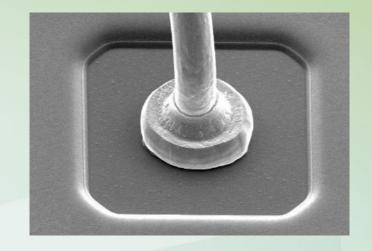
Temperature	Wafer Pass Die	PKG All Fail Die	PKG Speed Fail Die	Overall Correlation	Speed-only Correlation
125C	24705	268	41	98.92%	99.83%
-40C	24713	41	23	99.83%	99.90%

- Only 64 new fails. Induced by assy.?
- Example char mean deltas: -1.21-0.20%



Key Challenge: Pad Size Decreasing

- Pad size decreases as die size decreases and speed increases.
- Calculate parasitic capacitance: $C_p = \frac{(K \times \epsilon_o \times A)}{d}$
- Where:
 - K = dielectric constant (Si = 11.7)
 - ϵ_o = relative permittivity of free space (8.854 \times 10⁻¹² F/m)
 - A = Overlapping surface area of capacitor plates (mm2)
 - d = Distance between plates (mm), assume 5um



70x70um pad:

$$\frac{(11.7 \times 8.854 \times 10^{-12} \, F/m \times 0.490 mm^2)}{0.005 mm} = 10.2 pF$$

50x50um pad:

$$\frac{(11.7 \times 8.854 \times 10^{-12} \, F/m \times 0.250 mm^2)}{0.005 mm} = 5.18 pF$$

Benefit:

 Smaller bond pad size = less parasitic capacitance!

Challenge:

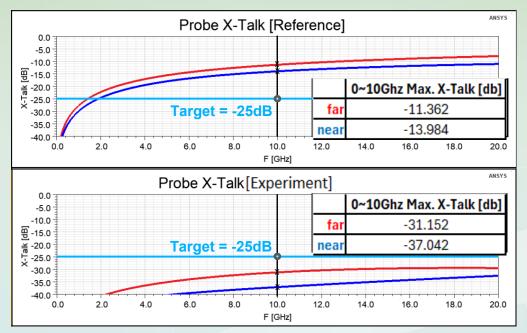
 Smaller pad size = smaller scrub and more accurate probe position required.

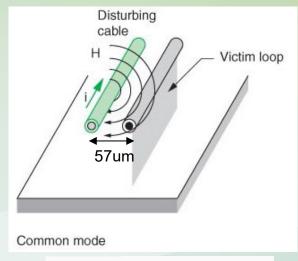
Key Challenge: Pad Pitch Decreasing

Example A:

Ground <u>not</u> fully shielding signal probes

Example B:Ground more fully shielding signal probes



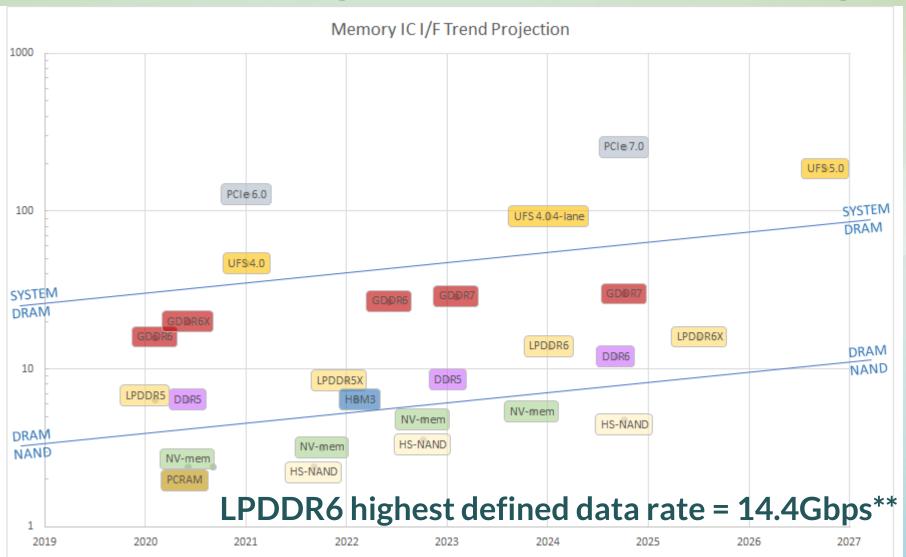


$$L \propto rac{1}{d} \quad V_{xtalk} = L \cdot rac{dI}{dt}$$

- Reducing pad pitch as die size shrinks, exacerbates crosstalk.
- Example B ideal case to minimize cross-talk.
- Any lessons from RF/other high-speed applications to apply to Memory probing?

 Class Conference | Carlsbad, CA, June 2 4, 2025

Key Challenge: Speed Increasing*



Summary / Conclusion

- High-speed wafer testing saves time-to-market for Memory Products.
- Volume monitoring key to accelerating design feedback.
- Continued advancement in probe card technology needed:

Challenge	Criteria / Target		
Low PDN target	Component & probe count		
Smaller pad size	Parasitic capacitance reduction		
Tighter pad pitch	Cross-talk between probes		
Higher speed	Device Datasheet Requirement		

Questions?

Thank You